

Customer No.: 07278



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kazuo Kasai, et al

Serial No.: 10/812,747

Group Art Unit: 1765

Filed: March 29, 2004

Examiner: VING, LAN

For: SILICON SUBSTRATE ETCHING METHOD AND ETCHING APPARATUS

STATUS REQUEST

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

To date, we have received no communication or official action from the Examiner in charge of the above-identified patent application. Please let us know the status of this case.

Respectfully submitted,

Dated: November 7, 2005

Chris T. Mizumoto
Reg. No. 42,899
Attorney for Applicant(s)

DARBY & DARBY P.C.
Post Office Box 5257
New York, NY 10150-5257
212-527-7700